

# SEMICAPS 4000

## INVERTED ANALYTICAL AND TESTER-DOCKED SYSTEM



### Features

- Analytical or ATE docked configuration
- 300 mm wafer stage including auto-lock compatible with Production Probe Cards and manipulators
- Docks easily to Tester or Probe Station
- High resolution stage with 0.5  $\mu\text{m}$  repeatability
- Centric and Aplanatic Refractive Solid Immersion Lens (RSIL) option
- CAD interface option
- Compatible with thermal management solutions
- Techniques include a combination of:
  - Laser Timing Probe (LTP)
  - Scanning Optical Microscopy (SOM) with best sensitivity
    - static: TIVA, OBIRCH
    - dynamic: LADA, SDL
  - Photon Emission Microscopy (PEM) with various options for the InGaAs or Si-CCD camera
  - Thermal Microscopy (THM) with InSb camera